



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : 10/678,045 Confirmation No. : 6655
First Named Inventor : Hiroshi SHINRIKI
Filed : October 3, 2003
TC/A.U. : 1762
Examiner : B. P. Chen

Docket No. : 010986.52822US
Customer No. : 23911

Title : Removing Oxide Film on a Substrate with Hydrogen
and Fluorine Radicals

LETTER

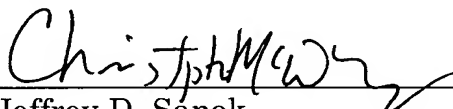
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

It is the understanding of the undersigned, after speaking with Examiner
Chen of the U.S. Patent and Trademark Office earlier this morning, Friday,
April 28, 2006, that this case is now in condition for allowance.

Respectfully submitted,

April 28, 2006


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